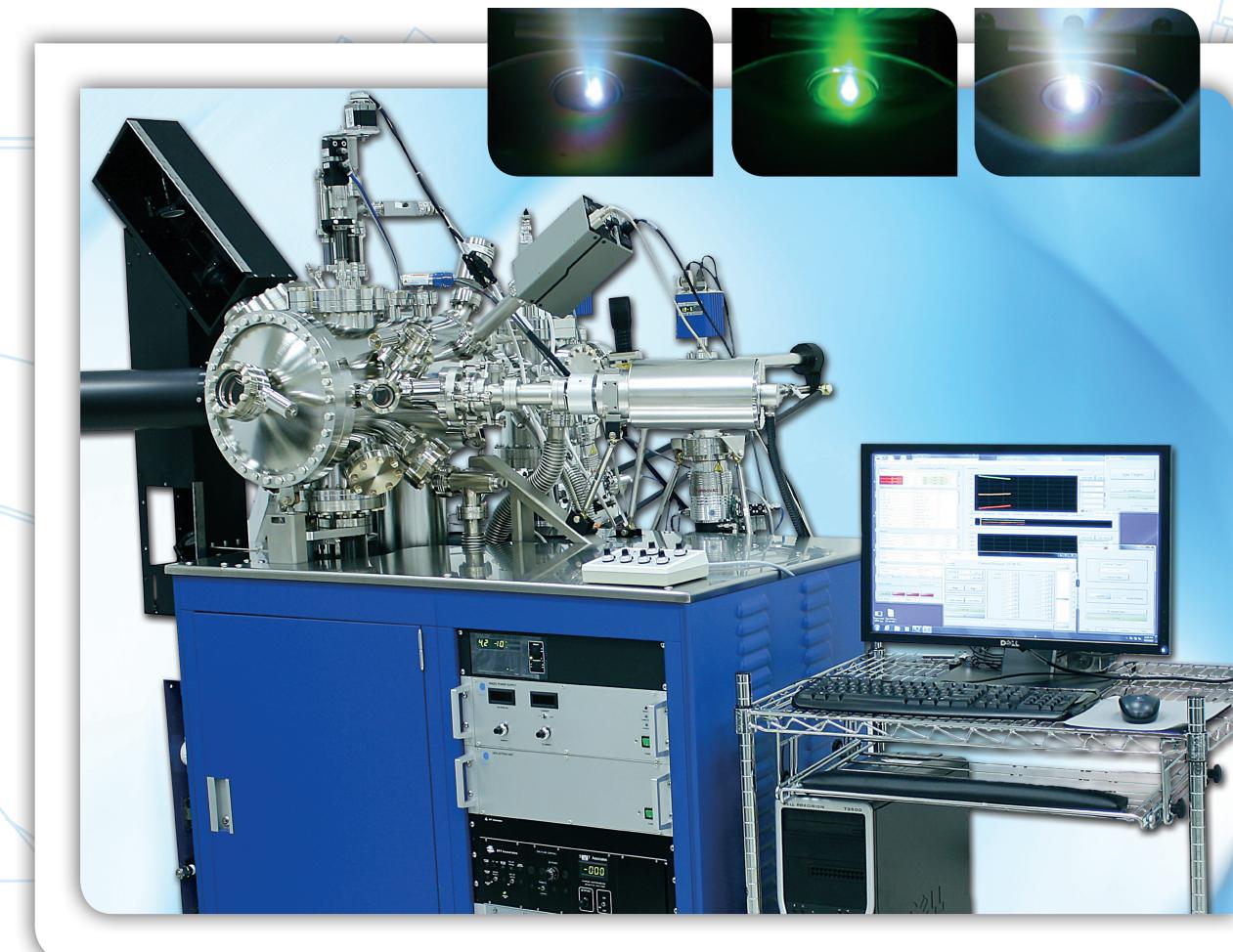
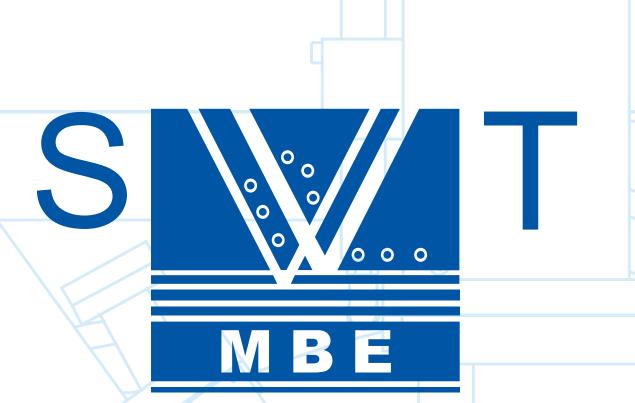


SMART NanoTool PLD

Versatile Research Pulsed Laser Deposition



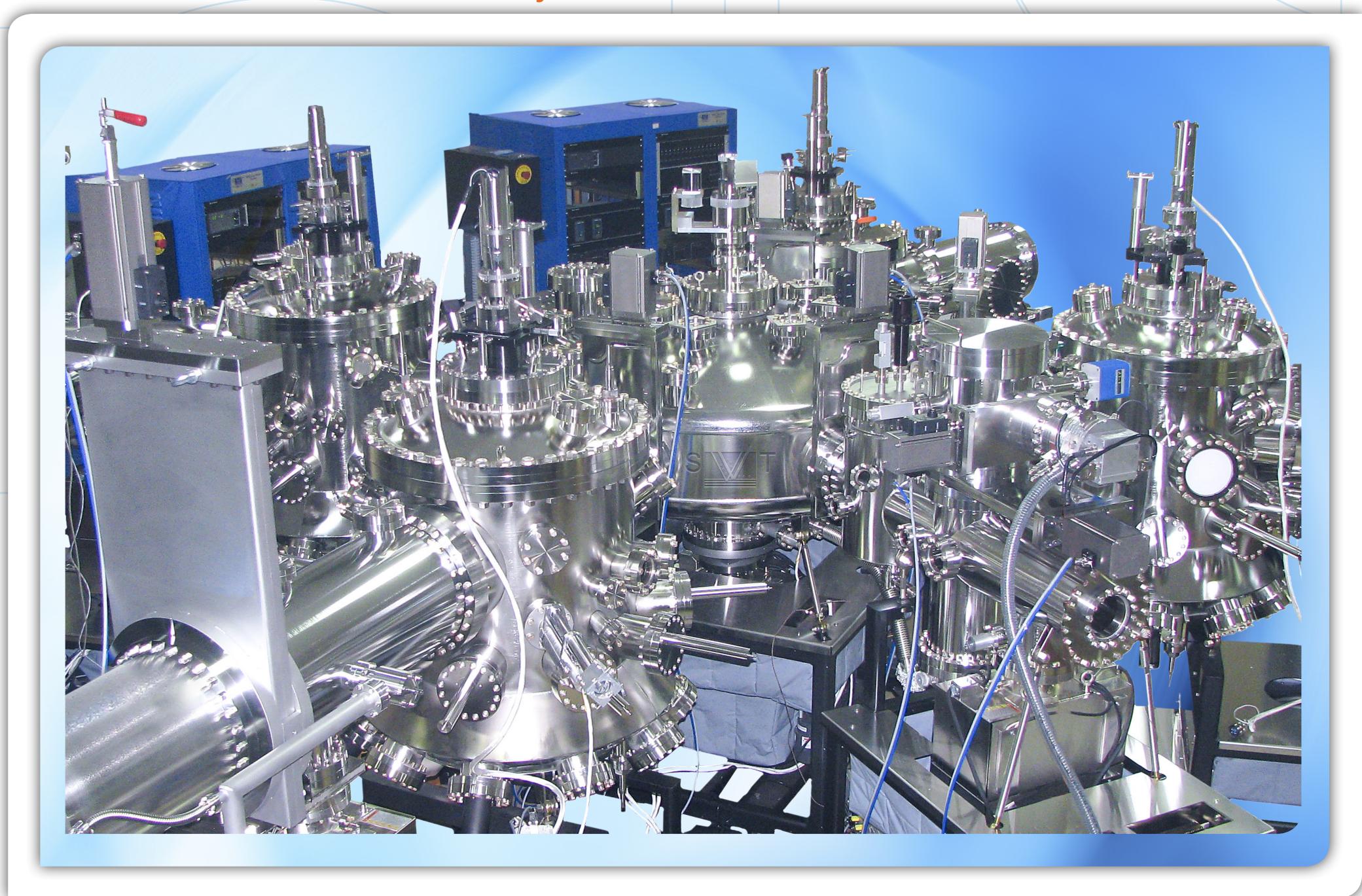
The SMART (Scientific Materials and Applied Research Tool) Pulsed Laser Deposition System is a unique research tool. Combining Laser Ablation with our unique deposition techniques offers a broad range of possible materials and



Standard Materials MBE

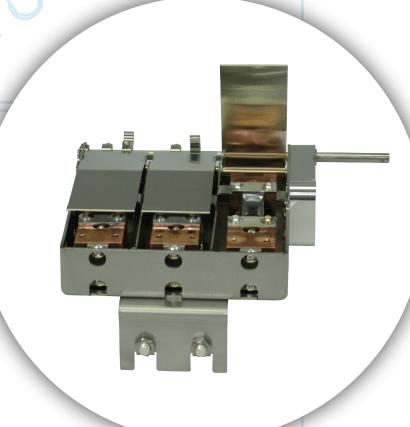
A versatile MBE system for research applications. The most complex compound semiconductor materials can be grown with 12 source ports. Designed to incorporate process monitoring tools. Up to 200 mm wafers.

MBE System with Cluster Tool

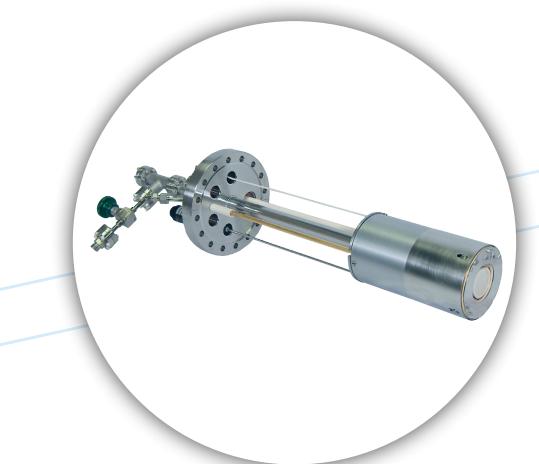




Effusion Cells



Therma
Boats



RF Plasma Sources

SMART

SMART NanoFab MBE

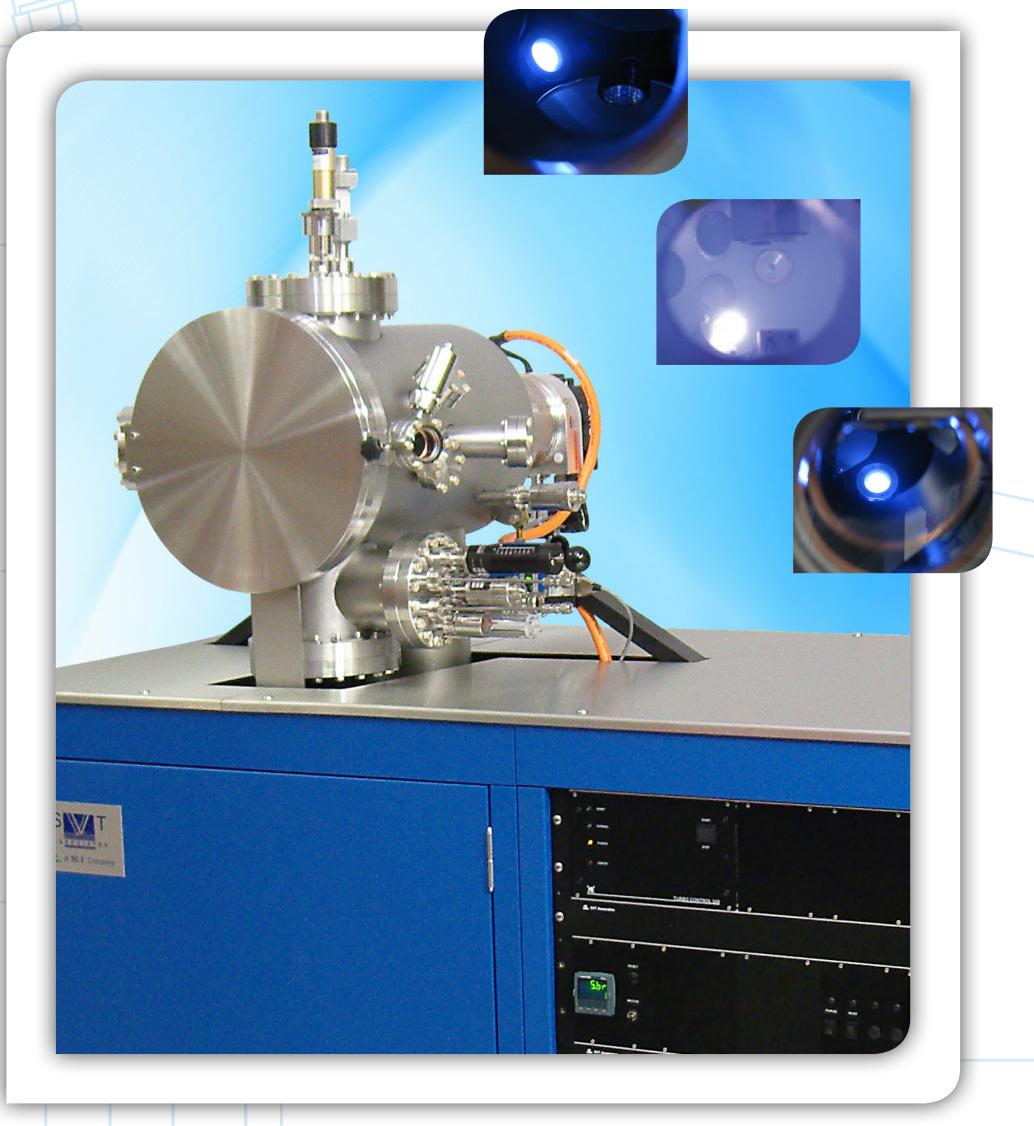


The SMART NanoFab MBE system is the perfect combination of small footprint and large capability. The table-top UHV chamber includes a series of ports to accommodate a wide selection of deposition sources and process monitoring tools.

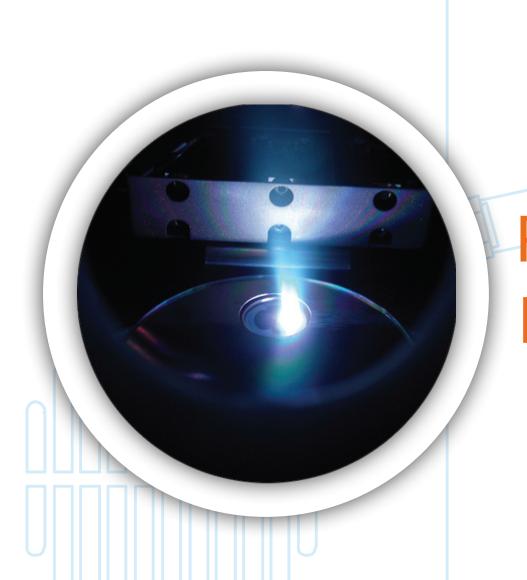


SMART Evaporation PVD

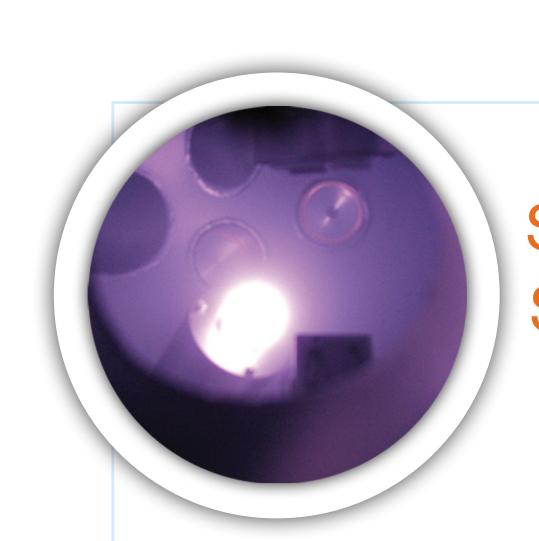
Versatile Research Physical Vapor Deposition



The SMART Physical Vapor Deposition
System combines multiple deposition
techniques in a single chamber allowing
researchers to continually develop complex
materials for the future as well as simple
processing techniques.

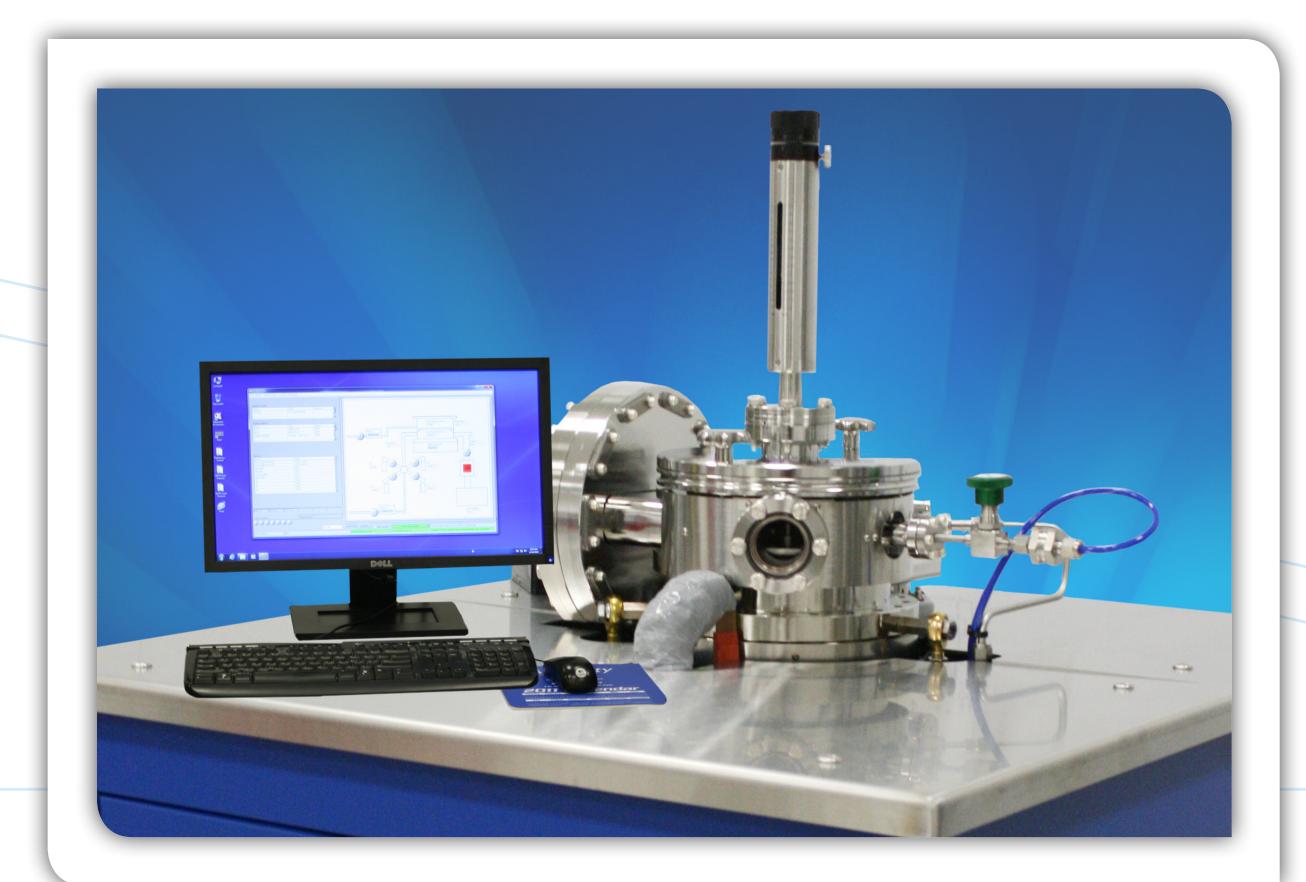


Pulsed Laser Deposition



Sputter
Sources





SVT Associates' Atomic Layer Deposition (ALD) system is a versatile research deposition tool for thermal or energy enhanced ALD





Electron Beam Evaporators

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